AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF THE CLAIMS

1. (withdrawn) An etching solution for etching an electrically resistive material including a nickel-chromium alloy, comprising:

hydrochloric acid; and thiourea.

- 2. (withdrawn) An etching solution according to claim 1, wherein said hydrochloric acid is in a range of 5 volume% to 95 volume%.
- 3. (withdrawn) An etching solution according to claim 2, wherein said hydrochloric acid is about 43 volume%.
- 4. (withdrawn) An etching solution according to claim 1 wherein said thiourea is in a range of 0.1 ppm to 100 grams/liter.
- 5. (withdrawn) An etching solution according to claim 4, wherein said thiourea is in a range of 1 ppm to 20 ppm.
- 6. (withdrawn) An etching solution according to claim 5, wherein said thiourea is in a range of 1 ppm to 2 ppm.
- 7. (withdrawn) An etching solution according to claim 1, wherein said solution further comprises glycerin.
- 8. (withdrawn) An etching solution according to claim 7, wherein said glycerin is in a range of 5 volume% to 95 volume%.

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9. (withdrawn) An etching solution according to claim 8, wherein said glycerin is

about 46 volume%.

10. (withdrawn) An etching solution according to claim 1, wherein said solution

further comprises water.

11. (withdrawn) An etching solution according to claim 10, wherein said water is in

a quantity sufficient to makeup 100% of volume% total.

12. (withdrawn) An etching solution according to claim 1, wherein said solution is

at a temperature in a range of room temperature to about boiling point temperature of said

solution.

13. (withdrawn) An etching solution according to claim 12, wherein said solution is

at a temperature in a range of 120°F to 180°F.

14. (withdrawn) An etching solution according to claim 13, wherein said solution is

at a temperature in a range of 140°F to 150°F.

15. (currently amended) A process for forming an embedded resistor from a

resistive foil having a copper layer and a resistive layer, wherein the resistive foil is bonded to a

dielectric layer, the method comprising:

selectively removing portions of the copper layer with a copper etchant to form trace

lines; and

selectively etching the resistive layer with an etchant comprised of hydrochloric acid,

glycerin and thiourea, wherein said hydrochloric acid is in a range of 5 volume% to 95 volume%,

said glycerin is in a range of 5 volume% to 95 volume%, and said thiourea is in a range of 0.1

ppm to 100 grams/liter.

- 16. (original) A process according to claim 15, wherein a photoresist is applied to the copper layer to define the trace lines.
- 17. (original) A process according to claim 16, wherein said photoresist is not removed prior to the selective etching of the resistive layer.
- 18. (original) A process according to claim 16, wherein said photoresist is removed prior to the selective etching of the resistive layer.

Claim 19 (canceled).

20. (currently amended) A process according to <u>claim 15</u> - <u>claim-19</u>, wherein said hydrochloric acid is about 43 volume%.

Claim 21 (canceled).

- 22. (currently amended) A process according to claim 15 claim 21, wherein said thiourea is in a range of 1 ppm to 20 ppm.
- 23. (original) A process according to claim 22, wherein said thiourea is in a range of 1 ppm to 2 ppm.

Claims 24-25 (canceled).

- 26. (currently amended) A process according to claim 15 claim 25, wherein said glycerin is about 46 volume%.
- 27. (original) A process according to claim 15, wherein said solution further comprises water.

- 28. (original) A process according to claim 27, wherein said water is in a quantity sufficient to makeup 100% of volume% total.
- 29. (original) A process according to claim 15, wherein said solution is at a temperature in a range of room temperature to about boiling point temperature of said solution.
- 30. (original) A process according to claim 29, wherein said solution is at a temperature in a range of 120°F to 180°F.
- 31. (original) A process according to claim 30, wherein said solution is at a temperature in a range of 140°F to 150°F.